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10/058426

01/30/02

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10058426	01/30/2002	430	311	1756	<i>Barreca</i>

**APPLICANTS: Komada Daisuke; Kakamu Katsumi;

CONTINUING DATA VERIFIED: *none* FOREIGN APPLICATIONS VERIFIED: *ny*

JAPAN 2001-312383 10/10/2001

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PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	ATTORNEY DOCKET NO
Foreign priority claimed	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no		
35 USC 119 conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no		
Verified and Acknowledged Examiners's initials	<i>ny</i>		020060
TITLE : Method of manufacturing semiconductor device having silicon carbide film			

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.G.
Assistant Examiner		DRAWING	
		Sheets Drwg.	Figs.Drwg. Print Fig.
Primary Examiner		Application Examiner	
PREPARED FOR ISSUE			
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ISSUE FEE

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